

AMENDMENT UNDER 37 C.F.R. § 1.116
EXPEDITED PROCEDURE
GROUP 2812
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q89627

Koichi TERASHIMA, et al.

Appln. No.: 10/544,783

Group Art Unit: 2812

Confirmation No.: 5339

Examiner: Pape A. SENE

Filed: August 8, 2005

For: METHOD FOR FORMING NICKEL SILICIDE FILM, METHOD FOR
MANUFACTURING SEMICONDUCTOR DEVICE, AND METHOD FOR ETCHING
NICKEL SILICIDE

RESPONSE UNDER 37 C.F.R. § 1.116

MAIL STOP AF

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

OK TO ENTER

Sir:

In response to the Office Action dated December 23, 2008, please amend the above-identified application as follows on the accompanying pages. A Petition and payment for a one month Extension of Time are being filed herewith, extending the time period for response to April 23, 2009. This Amendment is therefore timely filed.

TABLE OF CONTENTS

REMARKS2